

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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|------------------------------|---|---------------------|
| In re Application of: |) | PATENT APPLICATION |
| |) | |
| Inventor: Apostolos Voutsas |) | |
| |) | |
| Serial No.: Not Yet Assigned |) | Attorney Docket No. |
| |) | SLA 0592 |
| Filed: Herewith |) | |
| |) | |
| Title: METHOD FOR FORMING |) | |
| SILICON FILMS WITH TRACE |) | |
| IMPURITIES |) | |
| |) | |

DECLARATION FOR PATENT APPLICATION

As a below named inventor, I hereby declare that my residence, post office address and citizenship are as stated below next to my name; I believe that I am the original, first and sole inventor (if one name is listed below), or the first and joint inventor (if plural names are listed below), of the subject matter which is claimed and for which a patent is sought on the invention entitled,

**METHOD FOR FORMING SILICON FILMS
WITH TRACE IMPURITIES**

the specification of which (check applicable ones):

- ☒ is attached hereto;
- ☐ was filed with the above-identified "Filed" date and assigned the above-identified "Serial No.";
- ☐ was amended on (or amended through) _____.

09896-0000

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Same

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June 28, 2001
